

## Electronic Patent Application Fee Transmittal

Application Number:	10689617			
Filing Date:	22-Oct-2003			
Title of Invention:	Method for cleaning plasma etching apparatus, method for plasma etching, and method for manufacturing semiconductor device			
First Named Inventor:	Satoru Okamoto			
Filer:	John F. Hayden/Christine Tomlinson			
Attorney Docket Number:	12732-170001			
Filed as Large Entity				
<b>Utility Filing Fees</b>				
Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Basic Filing:				
Pages:				
Claims:				
Miscellaneous-Filing:				
Petition:				
Patent-Appeals-and-Interference:				
Post-Allowance-and-Post-Issuance:				
Extension-of-Time:				
Extension - 2 months with \$0 paid	1252	1	450	450

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
<b>Miscellaneous:</b>				
<b>Total in USD (\$)</b>				<b>450</b>